

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

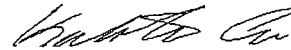
Applicant : Tetsuo SHIMOMURA et al.  
Appl. No. : 10/598,717  
Filed : September 8, 2006  
For : POLISHING PAD AND  
SEMICONDUCTOR DEVICE  
MANUFACTURING METHOD  
Examiner : Alvin J. Grant  
Group Art Unit : 3723

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Katsuhiro Arai, Reg.43,315

AMENDMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed July 27, 2007, please reconsider the present application in light of the following amendments and comments.

**Amendments to the Claims** are reflected in the listing of claims which begin on page 2 of this paper

**Remarks/Arguments** begin on page 7 of this paper.